## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s) : Aaron PARTRIDGE et al.

Serial No. : 10/713,172

Filing Date : November 14, 2003

For : CRACK AND RESIDUE FREE CONFORMAL

DEPOSITED SILICON OXIDE WITH

PREDICTABLE AND UNIFORM ETCHING

**CHARACTERISTICS** 

Examiner : Francis P. Smith

Group Art Unit : 1792 Confirmation No. : 9823

Customer No. : 26646

Mail Stop AF Commissioner for Patents P.O. Box 1450 Alexandria VA 22313-1450

I hereby certify that this correspondence is being electronically transmitted to the United States Patent and Trademark Office via the Office electronic filing system on February 17, 2009.

Signature: /Aaron Grunberger/

Aaron Grunberger (Reg. No. 59,210)

## **AMENDMENT AFTER FINAL OFFICE ACTION**

SIR:

In response to the Final Office Action of November 7, 2008, please reconsider the above-identified application based on the following.

**Amendments to the Claims** are reflected in the listing of the claims which begins on page 2 of this paper.

Remarks begin on page 10 of this paper.